

Some Critical Issues in the CLIC-SLAC-KEK Collaboration Structures

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Outline

- 1. Work Status
 - T24 Structures
 - Schedule toward the year 2010 end
 - Some Problems
 - TD24 couplers and others
- 2. Diffusion Bonding Quality
 - C10
 - TD18 and others

3. Surface Preparation – Etching Tests Revisit and Discussion



1. Work Status



- 1. T24_VG1.8 with SLAC flanges is under high power test at the NLCTA.
- 2. T24_VG1.8 with KEK flanges capped off with vacuum is supposed to be in Japan by now.
- 3. Fabrication of two TD24_VG1.8 structures with SLAC and KEK flanges is in the progress for assembly.
 - The one with SLAC flanges will be high power tested in the beginning of 2011.
 - The one with KEK flanges will be deliver it to KEK by the end of 2010.
- 4. The second CERN made T18 structure will be tested sometime in November or December of this year.

Tuning Status for T24_VG1.8

With SLAC Flanges Target frequency: 11424 MHz at 45°C and vacuum after tuning the frequency by 5.6 MHz higher. Filling time: 57.5 ns S11: ~ 0.01



S12: 0.73 (Alexej 0.755 5/29/2008)

With KEK Flanges Target frequency: 11424 MHz at 30°C and vacuum after tuning the frequency by 2.5 MHz higher. Filling time: 57.5 ns S11: ~ 0.025 S12: 0.72



Field Amplitude for T24_VG1.8



With SLAC Flanges



With KEK Flanges

Cell to Cell Phase for T24_VG1.8



With SLAC Flanges



With KEK Flanges

S Parameters for T24_VG1.8 with SLAC Flanges



S11 Measurement at NLCTA after Installation of the T24_VG1.8 with SLAC Flanges





Machining Marks in TD24_VG1.8 Coupler Bodies (4 each)





Measurement for Machining Marks in a TD24_VG1.8 Coupler Body





SLACE Enlarged View of Fine Machining Marks



- A 90 μin (2.3 μm Deep, 1 mm Wide) Groove;
- Milling machining marks are very small
- · Pursue coupler brazing due to the low field in the waveguide



2. Diffusion bonding quality



Cutoff Picture Reveals a Possible Bonding Problem





SEM Picture for Bonding Area in a C10 Structure



Drawing for a C10 Standard Cup





Metallographic Pictures for Bonding Area in a C10 Structure



- Very good bonding
- Corner radius is much smaller than drawing specified 0.005" (127 microns). The red bar is 254 microns.



CERN Pictures for **TD18** Structure after High Power Test Part C Down-stream side - Cell Wall S-W! Tilt 30° EHT = 5.00 kV TD18 KEK-SLAC Part C Tilt 3 100 µm WD = 15.4 mm Down-Stream -- Cell Wall S-V Signal A = SE2 Stage at R = 135.0 ° wall waveguide waveguide Mag = 200 X iris EHT = 5.00 kV TD18 KEK-SLAC Part C Tilt 30° 20 µm EN WD = 15.4 mm

Down-Stream -- Cell Wall S-W

Stage at R = 135.0 °

Signal A = SE2

Markus Aicheler

Date :30 Sep 2010



Drawing for TD18 Standard Cup





How much to Define the Bonding Corner Radius

The bonding corner radius seems to be a critical important dimension. It should be practically achievable and reasonable small. The followings are bonding corner radii in drawings for various structures:

 C10 (SLAC) 0.005" or 127 microns (actually machined < 20 microns)</td>

 T18 (KEK/SLAC)
 100 microns

 TD18 (KEK/SLAC)
 10 microns

 T24 (KEK/SLAC)
 100 microns

 TD24 (KEK/SLAC)
 10 microns

 T24 (CERN)
 50 microns



3. Surface Preparation – Etching Tests (2002) Revisit and Discussion



- Use 1" diameter coupons with raised ~ 1 cm² "mesa", using material stress-relieved in H₂.
- Finish-machine mesas with polycrystalline (T53) or single-crystal (LLNL) diamond tooling.
- Degrease with perchloro-ethylene, then etch individual coupons for 5, 30, 60 or 120 seconds. H₂-heat treat at 1020°C, 2 hours, followed by 950°C, 4 hours, to simulate degassing and brazing cycles.
- Analyze the mesas at each processing point with microbalance weighing, BSE, atomic force microscopy and, sometimes, XPS, SEM and optical microscopy.
 Done by R. Kirby, C. Pearson and F. Pimpec in 2002.



Microbalance Results







Poly-diamond-machined coupons were not stress-relieved before etching. Error bar on weight measurement is ~± 3.5 nm.



Single-Crystal Diamond Machining

SC-D #138



SC-D #139



SC-D #140

Etch 5 sec



5 seconds BSE image reveals grains;
10 seconds optical shows grain edges developing;
5 – 10 seconds etching is proper.

Etch 60 sec



Polycrystalline Diamond Machining





60 seconds BSE image reveals grains;60 -120 seconds optical shows grain edges developing;45 seconds or little more etching is proper.



Microbalance Results

Poly-diamond Machined

AFM Average Roughness Values

Coupon #	143	144	145	146
Bare machining (nm)	128.73	100.63	123.95	130
After ETCH (nm)	105.12 (5")	40.42 (30")	44.41 (60")	90.48 (120")
Heat treatment (nm)	67.15	35.63	31.32	53.06

SC-diamond Machined

Coupon #	137	138	139	140
Bare machining (nm)	4.73	6.27	8.67	3.35
After ETCH (nm)	4.74 (0")	6.32 (5")	12.46 (30")	21.33 (60")
Heat treatment (nm)	1	8.00	19.83	20.60





I'd like to confirm the time of heavier etching for TD24 Cups. 30 seconds?